



 Day : Saturday
 Date: 9/15/2007
 Time: 15:45:37

Inventor Name Search Result

Your Search was:

Last Name = TSUCHIYA

First Name = HIDEO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
07709020	Not Issued	166	05/31/1991	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	TSUCHIYA, HIDEO
07941197	5475766	150	09/04/1992	PATTERN INSPECTION APPARATUS WITH CORNER ROUNDING OF REFERENCE PATTERN DATA	TSUCHIYA, HIDEO
08025317	5577171	150	03/02/1993	FIGURE PATTERN GENERATING APPARATUS FOR DETECTING PATTERN DEFECTS	TSUCHIYA, HIDEO
08040852	5379348	150	03/31/1993	PATTERN DEFECTS INSPECTION SYSTEM	TSUCHIYA, HIDEO
08099409	Not Issued	166	07/30/1993	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	TSUCHIYA, HIDEO
08180813	5404410	250	01/10/1994	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	TSUCHIYA, HIDEO
08278141	Not Issued	161	07/21/1994	NON-WOVEN FABRIC AND METHOD OF PRODUCING THE SAME	TSUCHIYA, HIDEO
08413704	5960106	150	03/30/1995	SAMPLE INSPECTION APPARATUS AND SAMPLE INSPECTION METHOD	TSUCHIYA, HIDEO
08561390	5733625	150	11/21/1995	NON-WOVEN FABRIC	TSUCHIYA, HIDEO
08614063	5744381	150	03/12/1996	METHOD OF INSPECTING A PATTERN FORMED ON A SAMPLE FOR A DEFECT, AND AN APPARATUS THEREOF	TSUCHIYA, HIDEO
08937156	6285783	150	09/25/1997	PATTERN DATA GENERATING APPARATUS AND METHOD FOR INSPECTING DEFECTS IN FINE PATTERNS IN A PHOTOMASK OR SEMICONDUCTOR WAFER	TSUCHIYA, HIDEO
10106344	7020321	150	03/27/2002	PATTERN DATA CONVERTING METHOD AND APPARATUS	TSUCHIYA, HIDEO
10252718	6883160	150	09/24/2002	PATTERN INSPECTION APPARATUS	TSUCHIYA, HIDEO

<u>10627702</u>	<u>7068364</u>	150	07/28/2003	PATTERN INSPECTION APPARATUS	TSUCHIYA, HIDEO	
<u>10642760</u>	Not Issued	71	08/19/2003	Pattern inspection apparatus	TSUCHIYA, HIDEO	
<u>10743830</u>	Not Issued	41	12/24/2003	Pattern inspecting method and pattern inspecting apparatus	TSUCHIYA, HIDEO	
<u>11079338</u>	<u>7209584</u>	150	03/15/2005	PATTERN INSPECTION APPARATUS	TSUCHIYA, HIDEO	
<u>11265180</u>	<u>7275006</u>	150	11/03/2005	WORKPIECE INSPECTION APPARATUS ASSISTING DEVICE, WORKPIECE INSPECTION METHOD AND COMPUTER-READABLE RECORDING MEDIA STORING PROGRAM THEREFOR	TSUCHIYA, HIDEO	
<u>11674025</u>	Not Issued	71	02/12/2007	PATTERN INSPECTION APPARATUS	TSUCHIYA, HIDEO	

Inventor Search Completed: No Records to Display.

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Inventor Name Search Result

Your Search was:

Last Name = YAMASHITA

First Name = KYOJI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
07291276	4988197	150	12/28/1988	METHOD AND APPARATUS FOR ALIGNING TWO OBJECTS, AND METHOD AND APPARATUS FOR PROVIDING A DESIRED GAP BETWEEN TWO OBJECTS	YAMASHITA, KYOJI
07538186	5100234	150	06/13/1990	METHOD AND APPARATUS FOR ALIGNING TWO OBJECTS, AND METHOD AND APPARATUS FOR PROVIDING A DESIRED GAP BETWEEN TWO OBJECTS	YAMASHITA, KYOJI
07653236	5185812	150	02/11/1991	OPTICAL PATTERN INSPECTION SYSTEM	YAMASHITA, KYOJI
07709020	Not Issued	166	05/31/1991	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	YAMASHITA, KYOJI
08099409	Not Issued	166	07/30/1993	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	YAMASHITA, KYOJI
08180813	5404410	250	01/10/1994	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	YAMASHITA, KYOJI
08415928	5675168	150	04/03/1995	UNSYMMETRICAL MOS DEVICE HAVING A GATE INSULATOR AREA OFFSET FROM THE SOURCE AND DRAIN AREAS, AND ESD PROTECTION CIRCUIT INCLUDING SUCH A MOS DEVICE	YAMASHITA, KYOJI
08494384	5610430	150	06/26/1995	SEMICONDUCTOR DEVICE HAVING REDUCED GATE OVERLAPPING CAPACITANCE	YAMASHITA, KYOJI
08527902	Not Issued	161	09/14/1995	PHOTO-MASK INSPECTION APPARATUS AND METHOD	YAMASHITA, KYOJI
08664957	5841173	150	06/13/1996	MOS SEMICONDUCTOR DEVICE WITH EXCELLENT DRAIN CURRENT	YAMASHITA, KYOJI
08685726	6281562	150	07/24/1996	A SEMICONDUCTOR DEVICE WHICH REDUCES THE MINIMUM DISTANCE REQUIREMENTS BETWEEN ACTIVE	YAMASHITA, KYOJI

AREAS				
08687625	5844809	150	07/26/1996	METHOD AND APPARATUS FOR GENERATING TWO-DIMENSIONAL CIRCUIT PATTERN
08716571	5879983	150	09/18/1996	SEMICONDUCTOR DEVICE AND METHOD FOR MANUFACTURING THE SAME
08763801	5856754	150	12/11/1996	SEMICONDUCTOR INTEGRATED CIRCUIT WITH PARALLEL/SERIAL/PARALLEL CONVERSION
08767486	Not Issued	161	12/16/1996	SEMICONDUCTOR DEVICE HAVING REDUCED GATE OVERLAPPING CAPACITANCE
09092396	6205570	150	06/05/1998	METHOD FOR DESIGNING LSI CIRCUIT PATTERN
09112641	6084716	150	07/09/1998	OPTICAL SUBSTRATE INSPECTION APPARATUS
09158086	6396943	150	09/22/1998	DEFECT INSPECTION METHOD AND DEFECT INSPECTION APPARATUS
09166904	6594598	150	10/06/1998	METHOD FOR CONTROLLING PRODUCTION LINE
09192536	6124160	150	11/17/1998	SEMICONDUCTOR DEVICE AND METHOD FOR MANUFACTURING THE SAME
09629861	6492672	150	08/01/2000	SEMICONDUCTOR DEVICE
09902157	6709950	150	07/11/2001	SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE SAME
09960355	Not Issued	161	09/24/2001	Defect inspection apparatus and method
10232689	6876208	150	09/03/2002	SEMICONDUCTOR DEVICE AND METHOD OF CHECKING SEMICONDUCTOR STORAGE DEVICE
10252718	6883160	150	09/24/2002	PATTERN INSPECTION APPARATUS
10355068	6894520	150	01/31/2003	SEMICONDUCTOR DEVICE AND CAPACITANCE MEASUREMENT METHOD
10395342	7032208	150	03/25/2003	DEFECT INSPECTION APPARATUS
10454682	6967409	150	06/05/2003	SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE

				SAME	
<u>10642760</u>	Not Issued	71	08/19/2003	Pattern inspection apparatus	YAMASHITA, KYOJI
<u>10760449</u>	7230435	150	01/21/2004	CAPACITANCE MEASUREMENT CIRCUIT	YAMASHITA, KYOJI
<u>10777068</u>	6982555	150	02/13/2004	SEMICONDUCTOR DEVICE	YAMASHITA, KYOJI
<u>10991457</u>	Not Issued	41	11/19/2004	Method for evaluating semiconductor device	YAMASHITA, KYOJI
<u>10995283</u>	7126174	150	11/24/2004	SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE SAME	YAMASHITA, KYOJI
<u>11079338</u>	7209584	150	03/15/2005	PATTERN INSPECTION APPARATUS	YAMASHITA, KYOJI
<u>11080456</u>	Not Issued	61	03/16/2005	Method for variability constraints in design of integrated circuits especially digital circuits which includes timing closure upon placement and routing of digital circuit or network	YAMASHITA, KYOJI
<u>11081679</u>	Not Issued	161	03/17/2005	Semiconductor device and method of manufacturing the same	YAMASHITA, KYOJI
<u>11101466</u>	Not Issued	41	04/08/2005	Semiconductor integrated circuit design method, design support system for the same, and delay library	YAMASHITA, KYOJI
<u>11138499</u>	7171640	150	05/27/2005	SYSTEM AND METHOD FOR OPERATION VERIFICATION OF SEMICONDUCTOR INTEGRATED CIRCUIT	YAMASHITA, KYOJI
<u>11148208</u>	Not Issued	95	06/09/2005	SEMICONDUCTOR DEVICE	YAMASHITA, KYOJI
<u>11202210</u>	Not Issued	30	08/12/2005	Semiconductor device and layout design method for the same	YAMASHITA, KYOJI
<u>11270602</u>	Not Issued	30	11/10/2005	Semiconductor device and method for fabricating the same	YAMASHITA, KYOJI
<u>11270662</u>	Not Issued	41	11/10/2005	Semiconductor integrated circuit and method for designing the same	YAMASHITA, KYOJI
<u>11287419</u>	Not Issued	30	11/28/2005	Sample inspection apparatus, image alignment method, and program-recorded readable recording medium	YAMASHITA, KYOJI
<u>11334506</u>	Not Issued	30	01/19/2006	Semiconductor integrated circuit designing method and library designing method	YAMASHITA, KYOJI
<u>11349077</u>	Not Issued	41	02/08/2006	Circuit simulation method and circuit simulation apparatus	YAMASHITA, KYOJI
<u>11518199</u>	Not	30	09/11/2006	Design method for semiconductor integrated	YAMASHITA, KYOJI

	Issued			circuit	
<u>11553711</u>	Not Issued	30	10/27/2006	DATA SEARCHING SYSTEM, METHOD OF SYNCHRONIZING METADATA AND DATA SEARCHING APPARATUS	<u>YAMASHITA, KYOJI</u>
<u>11591452</u>	Not Issued	30	11/02/2006	Semiconductor circuit device and design method therefor	<u>YAMASHITA, KYOJI</u>
<u>11674025</u>	Not Issued	71	02/12/2007	PATTERN INSPECTION APPARATUS	<u>YAMASHITA, KYOJI</u>
<u>11678748</u>	Not Issued	30	02/26/2007	TARGET WORKPIECE INSPECTION APPARATUS, IMAGE ALIGNMENT METHOD, AND COMPUTER-READABLE RECORDING MEDIUM WITH PROGRAM RECORDED THEREON	<u>YAMASHITA, KYOJI</u>

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Inventor Name Search Result

Your Search was:

Last Name = WATANABE

First Name = TOSHIYUKI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
06075661	4268665	150	09/14/1979	DERIVATIVES OF ANTIBIOTIC TYLOSIN	WATANABE, TOSHIYUKI
06091663	4264723	150	11/05/1979	SILVER HALIDE COLOR PHOTOGRAPHIC MATERIALS	WATANABE, TOSHIYUKI
06104999	4282312	150	12/18/1979	COLOR IMAGE FORMING PROCESS	WATANABE, TOSHIYUKI
06126934	4310619	150	03/03/1980	COLOR PHOTGRAPHIC MATERIAL AND PROCESS INCORPORATING A NOVEL MAGENTA COUPLER	WATANABE, TOSHIYUKI
06168616	Not Issued	161	07/14/1980	AIR CONTROL ATTACHMENT FOR THE FRONT OF A VEHICLE, OR SIMILAR ARTICLE	WATANABE, TOSHIYUKI
06168617	Not Issued	161	07/14/1980	AIR CONTROL ATTACHMENT FOR THE REAR OF A VEHICLE, OR SIMILAR ARTICLE	WATANABE, TOSHIYUKI
06168618	D267864	150	07/14/1980	MUDGUARD FOR A VEHICLE, OR SIMILAR ARTICLE	WATANABE, TOSHIYUKI
06216714	4310623	150	12/15/1980	COLOR PHOTOGRAPHIC LIGHT-SENSITIVE MATERIAL	WATANABE, TOSHIYUKI
06243159	4407936	150	03/12/1981	PROCESS AND MATERIAL FOR FORMING COLOR PHOTOGRAPHIC IMAGE	WATANABE, TOSHIYUKI
06326208	Not Issued	166	12/01/1981	ORAL COMPOSITION	WATANABE, TOSHIYUKI
06356076	4454521	150	03/08/1982	IAZOTYPE THERMOSENSITIVE RECORDING MATERIAL	WATANABE, TOSHIYUKI
06412406	Not Issued	161	08/27/1982	IAZOTYPE THERMOSENSITIVE RECORDING MATERIAL	WATANABE, TOSHIYUKI
06440044	4411987	150	11/08/1982	SILVER HALIDE COLOR PHOTOGRAPHIC LIGHT-SENSITIVE MATERIAL	WATANABE, TOSHIYUKI
06496289	Not Issued	166	05/19/1983	RETURNABLE BOX	WATANABE, TOSHIYUKI

<u>06497636</u>	<u>4522915</u>	150	05/24/1983	COLOR PHOTOGRAPHIC SILVER HALIDE LIGHT-SENSITIVE MATERIALS CONTAINING NOVEL MAGENTA COLOR-FORMING COUPLERS	WATANABE, TOSHIYUKI
<u>06516869</u>	Not Issued	161	07/26/1983	ORAL COMPOSITION	WATANABE, TOSHIYUKI
<u>06537609</u>	<u>4532807</u>	150	09/30/1983	METHOD AND APPARATUS FOR DETECTING SOUND SOURCE	WATANABE, TOSHIYUKI
<u>06571762</u>	Not Issued	161	01/18/1984	SILVER HALIDE COLOR PHOTOGRAPHIC LIGHT-SENSITIVE MATERIALS	WATANABE, TOSHIYUKI
<u>06572048</u>	<u>4567135</u>	150	01/19/1984	SILVER HALIDE COLOR PHOTOGRAPHIC LIGHT-SENSITIVE MATERIAL	WATANABE, TOSHIYUKI
<u>06572049</u>	<u>4536472</u>	150	01/19/1984	SILVER HALIDE COLOR PHOTOGRAPHIC LIGHT-SENSITIVE MATERIAL	WATANABE, TOSHIYUKI
<u>06636290</u>	<u>4630813</u>	150	07/31/1984	METHOD OF AND DEVICE FOR DETECTING DISPLACEMENT OF PAPER SHEETS	WATANABE, TOSHIYUKI
<u>06645148</u>	<u>4579813</u>	150	08/28/1984	SILVER HALIDE COLOR PHOTOGRAPHIC MATERIALS	WATANABE, TOSHIYUKI
<u>06667445</u>	<u>4589768</u>	150	11/01/1984	ORIGINAL TRANSFER APPARATUS	WATANABE, TOSHIYUKI
<u>06696545</u>	<u>4578346</u>	150	01/30/1985	SILVER HALIDE COLOR PHOTOGRAPHIC LIGHT-SENSITIVE MATERIALS	WATANABE, TOSHIYUKI
<u>06797194</u>	Not Issued	166	11/13/1985	RETURNABLE BOX	WATANABE, TOSHIYUKI
<u>06855299</u>	Not Issued	161	04/24/1986	TITANIUM ALLOYS HAVING AN EXCELLENT COLD WORKABILITY	WATANABE, TOSHIYUKI
<u>06869805</u>	Not Issued	161	05/29/1986	RETURNABLE BOX	WATANABE, TOSHIYUKI
<u>06901224</u>	<u>4764456</u>	150	08/28/1986	SILVER HALIDE COLOR PHOTOGRAPHIC MATERIAL	WATANABE, TOSHIYUKI
<u>06906311</u>	<u>4785862</u>	150	09/11/1986	DUAL TIRE MOUNTING METHOD	WATANABE, TOSHIYUKI
<u>06917092</u>	Not Issued	166	11/24/1986	SILVER HALIDE PHOTOGRAPHIC LIGHT-SENSITIVE MATERIAL	WATANABE, TOSHIYUKI
<u>06947302</u>	<u>4783397</u>	150	12/29/1986	SILVER HALIDE COLOR PHOTOGRAPHIC MATERIAL CONTAINING A COUPLER FOR FORMING A YELLOW DYE, AND A PROCESS FOR PRODUCING YELLOW	WATANABE, TOSHIYUKI

IMAGES USING THE SAME					
07003773	4735288	150	01/16/1987	DETACHABLY ATTACHING MECHANISM FOR CUP OF LUBRICATOR OR FILTER USED WITH AIR-ACTUATED DEVICE	WATANABE, TOSHIYUKI
07052881	4874689	150	05/22/1987	SILVER HALIDE COLOR PHOTOGRAPHIC MATERIAL	WATANABE, TOSHIYUKI
07088318	Not Issued	161	08/24/1987	LIGHT-SENSITIVE MATERIAL CONTAINING SILVER HALIDE, REDUCING AGENT AND POLYMERIZABLE COMPOUND	WATANABE, TOSHIYUKI
07102193	4892681	250	09/29/1987	NON-LINEAR OPTICAL ARTICLE	WATANABE, TOSHIYUKI
07109886	Not Issued	166	10/19/1987	LIGHT-SENSITIVE MATERIAL CONTAINING SILVER HALIDE, REDUCING AGENT AND POLYMERIZABLE COMPOUND	WATANABE, TOSHIYUKI
07115064	4775656	150	10/30/1987	RECORDING MATERIAL CONTAINING LEUCO DYE	WATANABE, TOSHIYUKI
07115067	Not Issued	166	10/30/1987	LIGHT-SENSITIVE MATERIAL CONTAINING SILVER HALIDE, REDUCING AGENT AND POLYMERIZABLE COMPOUND	WATANABE, TOSHIYUKI
07122807	Not Issued	166	11/19/1987	LIGHT-SENSITIVE MATERIAL CONTAINING SILVER HALIDE, REDUCING AGENT AND POLYMERIZABLE COMPOUND	WATANABE, TOSHIYUKI
07199078	4844568	150	05/26/1988	SCANNING TYPE PROJECTION EXPOSURE SYSTEM	WATANABE, TOSHIYUKI
07199635	4997741	150	05/27/1988	COLOR IMAGE FORMING METHOD USING LEUCO DYES AND RECORDING MATERIAL CONTAINING LEUCO DYES	WATANABE, TOSHIYUKI
07309905	4925782	150	02/13/1989	SILVER HALIDE PHOTOGRAPHIC LIGHT-SENSITIVE ELEMENT CONTAINING WATER SOLUBLE DYE COMPOUNDS	WATANABE, TOSHIYUKI
07350684	D315758	150	05/10/1989	TOY AIRPLANE COCKPIT	WATANABE, TOSHIYUKI
07362464	5045239	250	03/17/1989	NON-LINEAR OPTICAL MATERIAL	WATANABE, TOSHIYUKI
07373131	5110988	150	06/29/1989	NONLINEAR OPTICAL MATERIAL	WATANABE, TOSHIYUKI
07391663	4959291	150	08/08/1989	LIGHT-SENSITIVE MATERIAL CONTAINING SILVER HALIDE,	WATANABE, TOSHIYUKI

				REDUCING AGENT, POLYMERIZABLE COMPOUND AND A DIAZAPHTHALIDE DYE	
07489752	Not Issued	161	02/26/1990	LIGHT-SENSITIVE MATERIAL	WATANABE, TOSHIYUKI
07565088	Not Issued	166	08/10/1990	SILVER HALIDE PHOTOGRAPHIC LIGHT-SENSITIVE MATERIALS	WATANABE, TOSHIYUKI
07604400	5030543	150	10/29/1990	LIGHT-SENSITIVE MATERIAL CONTAINING SILVER HALIDE, REDUCING AGENT AND POLYMERIZABLE COMPOUND	WATANABE, TOSHIYUKI
07621427	5159483	150	12/05/1990	PROJECTING AND EXPOSING DEVICE	WATANABE, TOSHIYUKI

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Inventor Name Search Result

Your Search was:

Last Name = ISOMURA

First Name = IKUNAO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
08937156	6285783	150	09/25/1997	PATTERN DATA GENERATING APPARATUS AND METHOD FOR INSPECTING DEFECTS IN FINE PATTERNS IN A PHOTOMASK OR SEMICONDUCTOR WAFER	ISOMURA, IKUNAO
10642760	Not Issued	71	08/19/2003	Pattern inspection apparatus	ISOMURA, IKUNAO
10720136	Not Issued	71	11/25/2003	Pattern inspection apparatus	ISOMURA, IKUNAO
10809409	Not Issued	61	03/26/2004	Pattern inspection apparatus	ISOMURA, IKUNAO
11072317	Not Issued	30	03/07/2005	Defect inspection apparatus and defect inspection method	ISOMURA, IKUNAO
11083202	Not Issued	61	03/18/2005	Mask defect inspection apparatus	ISOMURA, IKUNAO
11083323	Not Issued	71	03/18/2005	Mask-defect inspecting apparatus	ISOMURA, IKUNAO
11175360	Not Issued	30	07/07/2005	Pattern inspecting method	ISOMURA, IKUNAO
11276426	Not Issued	30	02/28/2006	PATTERN INSPECTION APPARATUS, PATTERN INSPECTION METHOD AND PROGRAM	ISOMURA, IKUNAO
11283755	Not Issued	30	11/22/2005	Pattern inspection apparatus, pattern inspection method, and program-recorded readable recording medium	ISOMURA, IKUNAO
11284186	Not Issued	30	11/22/2005	Pattern inspection apparatus, pattern inspection method, and program-recorded readable recording medium	ISOMURA, IKUNAO
11674025	Not Issued	71	02/12/2007	PATTERN INSPECTION APPARATUS	ISOMURA, IKUNAO

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Inventor Name Search Result

Your Search was:

Last Name = TOJO

First Name = TORU

Application#	Patent#	Status	Date Filed	Title	Inventor Name
06082226	4262974	150	10/04/1979	LINEAR BEARING APPARATUS	TOJO, TORU
06250386	4408126	150	04/02/1981	CASSETTE RETAINING DEVICE OF ELECTRON BEAM APPARATUS	TOJO, TORU
06374724	4469949	150	05/04/1982	ELECTRON BEAM PATTERN TRANSFER DEVICE AND METHOD FOR ALIGNING MASK AND SEMICONDUCTOR WAFER	TOJO, TORU
06379712	4467210	150	05/19/1982	ELECTRON-BEAM IMAGE TRANSFER DEVICE	TOJO, TORU
06428341	4480284	150	09/29/1982	ELECTROSTATIC CHUCK PLATE	TOJO, TORU
06429230	4455501	150	09/30/1982	PRECISION ROTATION MECHANISM	TOJO, TORU
06495486	4532423	150	05/17/1983	IC TESTER USING AN ELECTRON BEAM CAPABLE OF EASILY SETTING A PROBE CARD UNIT FOR WAFERS AND PACKAGED IC'S TO BE TESTED	TOJO, TORU
06525419	4572956	150	08/22/1983	ELECTRON BEAM PATTERN TRANSFER SYSTEM HAVING AN AUTOFOCUSING MECHANISM	TOJO, TORU
06527486	4558225	150	08/29/1983	TARGET BODY POSITION MEASURING METHOD FOR CHARGED PARTICLE BEAM FINE PATTERN EXPOSURE SYSTEM	TOJO, TORU
06664964	4578607	150	10/26/1984	PIEZOELECTRIC PRECISE ROTATION MECHANISM FOR SLIGHTLY ROTATING AN OBJECT	TOJO, TORU
06789086	Not Issued	166	10/18/1985	POSITION DETECTOR BY VIBRATING A LIGHT BEAM FOR AVERAGING THE REFLECTED LIGHT	TOJO, TORU
07009628	4698513	150	01/23/1987	POSITION DETECTOR BY VIBRATING	TOJO, TORU

				A LIGHT BEAM FOR AVERAGING THE REFLECTED LIGHT	
<u>07012282</u>	Not Issued	166	02/09/1987	METHOD FOR ALIGNING FIRST AND SECOND OBJECTS RELATIVE TO EACH OTHER, AND APPARATUS FOR PRACTICING THIS METHOD	TOJO, TORU
<u>07051709</u>	Not Issued	161	05/20/1987	METHOD FOR TRANSFERRING PATTERNS AND APPARATUS FOR TRANSFERRING PATTERNS	TOJO, TORU
<u>07167233</u>	4808002	150	03/11/1988	METHOD AND DEVICE FOR ALIGNING FIRST AND SECOND OBJECTS RELATIVE TO EACH OTHER	TOJO, TORU
<u>07214821</u>	4811062	150	07/01/1988	METHOD FOR ALIGNING FIRST AND SECOND OBJECTS RELATIVE TO EACH OTHER AND APPARATUS FOR PRACTICING THIS METHOD	TOJO, TORU
<u>07251842</u>	4902133	150	09/30/1988	METHOD AND AN APPARATUS FOR ALIGNING FIRST AND SECOND OBJECTS WITH EACH OTHER	TOJO, TORU
<u>07453856</u>	4984890	150	12/20/1989	METHOD AND AN APPARATUS FOR ALIGNING FIRST AND SECOND OBJECTS WITH EACH OTHER	TOJO, TORU
<u>07709020</u>	Not Issued	166	05/31/1991	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	TOJO, TORU
<u>08040852</u>	5379348	150	03/31/1993	PATTERN DEFECTS INSPECTION SYSTEM	TOJO, TORU
<u>08099409</u>	Not Issued	166	07/30/1993	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	TOJO, TORU
<u>08180813</u>	5404410	250	01/10/1994	METHOD AND SYSTEM FOR GENERATING A BIT PATTERN	TOJO, TORU
<u>08413174</u>	Not Issued	166	03/29/1995	SAMPLE INSPECTION APPARATUS AND SAMPLE INSPECTION METHOD	TOJO, TORU
<u>08413704</u>	5960106	150	03/30/1995	SAMPLE INSPECTION APPARATUS AND SAMPLE INSPECTION METHOD	TOJO, TORU
<u>08527633</u>	5602645	150	09/13/1995	PATTERN EVALUATION APPARATUS AND A METHOD OF PATTERN EVALUATION	TOJO, TORU
<u>08614063</u>	5744381	150	03/12/1996	METHOD OF INSPECTING A PATTERN FORMED ON A SAMPLE FOR A DEFECT, AND AN APPARATUS THEREOF	TOJO, TORU
<u>08748898</u>	5812259	150	11/15/1996	METHOD AND APPARATUS FOR	TOJO, TORU

				INSPECTING SLIGHT DEFECTS IN A PHOTOMASK PATTERN	
<u>08841762</u>	<u>5912468</u>	150	04/28/1997	CHARGED PARTICLE BEAM EXPOSURE SYSTEM	TOJO, TORU
<u>08854750</u>	<u>5828457</u>	150	05/12/1997	SAMPLE INSPECTION APPARATUS AND SAMPLE INSPECTION METHOD	TOJO, TORU
<u>09038037</u>	<u>6090176</u>	150	03/11/1998	SAMPLE TRANSFERRING METHOD AND SAMPLE TRANSFER SUPPORTING APPARATUS	TOJO, TORU
<u>09038038</u>	<u>6182369</u>	150	03/11/1998	PATTERN FORMING APPARATUS	TOJO, TORU
<u>09040286</u>	<u>6239443</u>	150	03/18/1998	APPARATUS FOR EMITTING A BEAM TO A SAMPLE USED FOR MANUFACTURING A SEMICONDUCTOR DEVICE	TOJO, TORU
<u>09040391</u>	<u>6080990</u>	150	03/18/1998	POSITION MEASURING APPARATUS	TOJO, TORU
<u>09112641</u>	<u>6084716</u>	150	07/09/1998	OPTICAL SUBSTRATE INSPECTION APPARATUS	TOJO, TORU
<u>09274304</u>	Not Issued	161	03/23/1999	SEMICONDUCTOR SUBSTRATE TRANSPORT SYSTEM UTILIZING LOCAL CLEANING TECHNOLOGY	TOJO, TORU
<u>09496643</u>	<u>6411023</u>	150	02/03/2000	VACUUM PROCESSING APPARATUS AND ION PUMP CAPABLE OF SUPPRESSING LEAKAGE OF IONS AND ELECTRONS FROM ION PUMP	TOJO, TORU
<u>09533265</u>	<u>6346354</u>	150	03/20/2000	Pattern writing method	TOJO, TORU
<u>09562181</u>	<u>6281510</u>	150	05/02/2000	Sample transferring method and sample transfer supporting apparatus	TOJO, TORU
<u>09933719</u>	<u>6676289</u>	150	08/22/2001	TEMPERATURE MEASURING METHOD IN PATTERN DRAWING APPARATUS	TOJO, TORU
<u>10397288</u>	<u>6901314</u>	150	03/27/2003	ALIGNMENT APPARATUS FOR SUBSTRATES	TOJO, TORU
<u>10642760</u>	Not Issued	71	08/19/2003	Pattern inspection apparatus	TOJO, TORU
<u>10720136</u>	Not Issued	71	11/25/2003	Pattern inspection apparatus	TOJO, TORU
<u>10809409</u>	Not Issued	61	03/26/2004	Pattern inspection apparatus	TOJO, TORU
<u>10852434</u>	Not Issued	89	05/25/2004	Inspection apparatus having two sensors, method for inspecting an object, and a	TOJO, TORU

				method for manufacturing a photolithography mask	
<u>10897120</u>	<u>7123345</u>	150	07/23/2004	AUTOMATIC FOCUSING APPARATUS	TOJO, TORU
<u>11012257</u>	<u>7075621</u>	150	12/16/2004	ALIGNMENT METHOD	TOJO, TORU
<u>11072317</u>	Not Issued	30	03/07/2005	Defect inspection apparatus and defect inspection method	TOJO, TORU
<u>11175360</u>	Not Issued	30	07/07/2005	Pattern inspecting method	TOJO, TORU
<u>11248124</u>	Not Issued	30	10/13/2005	Defect inspecting apparatus and defect inspection method	TOJO, TORU
<u>11249359</u>	Not Issued	30	10/14/2005	Defect inspecting apparatus	TOJO, TORU

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09956010	6909501	150	09/20/2001	PATTERN INSPECTION APPARATUS AND PATTERN INSPECTION METHOD	SANADA, YASUSHI
10627702	7068364	150	07/28/2003	PATTERN INSPECTION APPARATUS	SANADA, YASUSHI
10642760	Not Issued	71	08/19/2003	Pattern inspection apparatus	SANADA, YASUSHI
10743830	Not Issued	41	12/24/2003	Pattern inspecting method and pattern inspecting apparatus	SANADA, YASUSHI
11444488	Not Issued	30	06/01/2006	Battery pack of assembled battery and fixing method of assembled battery	SANADA, YASUSHI
11444492	Not Issued	25	06/01/2006	Battery pack	SANADA, YASUSHI
11674025	Not Issued	71	02/12/2007	PATTERN INSPECTION APPARATUS	SANADA, YASUSHI

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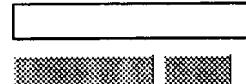
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IEEE JNL IEEE Journal or Magazine

IET JNL IET Journal or Magazine

IEEE CNF IEEE Conference Proceeding

IET CNF IET Conference Proceeding

IEEE STD IEEE Standard

[Select All](#) [Deselect All](#)**1. A golden block self-generating scheme for continuous patterned wafer inspections**

Sheng-Uei Guan; Pin Xie;
[Image Analysis and Processing, 1999. Proceedings. International Conference on](#)
27-29 Sept. 1999 Page(s):436 - 441
Digital Object Identifier 10.1109/ICIAP.1999.797634
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2. Automated direct patterned wafer inspection

Khalaj, B.H.; Aghajan, H.K.; Kailath, T.;
[Applications of Computer Vision, Proceedings, 1992. IEEE Workshop on](#)
30 Nov.-2 Dec. 1992 Page(s):266 - 273
Digital Object Identifier 10.1109/ACV.1992.240303
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A golden block self-generating scheme for continuous patterned wafer inspections

Sheng-Wei Guan Pin Xie

Dept. of Electr. Eng., Nat. Univ. of Singapore, Singapore;

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Abstract

This paper presents a novel technique for detecting defects in periodic 2D wafer images when there is no image database or priori knowledge. It creates a golden block database from the wafer image itself and customizes its content when needed. Spectral estimation is used in the first step to derive the periods of **repeated patterns** in both directions. Then a building block representing the structure of the patterns is extracted. After that, a new defect-free image is built based on this building block. Finally, a pixel-to-pixel comparison is all we need to find out possible defects. The extracted building block is stored as the golden block for a certain pattern. When a new image with the same periodical pattern arrives, we do not have to re-calculate its periods and building block. They can be derived directly from the existing golden block. It is a bridge between the existing self-reference methods and image-to-image reference methods

Index Terms**Inspec****Controlled Indexing**[automatic optical inspection](#) [feature extraction](#) [image representation](#) [integrated circuit yield](#) [manufacturing data processing](#) [parameter estimation](#) [spectral analysis](#)**Non-controlled Indexing**[continuous patterned wafer inspections](#) [defect detection](#) [defect-free image](#) [golden block self-generating scheme](#) [image-to-image reference methods](#) [pattern extraction](#) [periodic 2D wafer images](#) [pixel-to-pixel comparison](#) [self-reference methods](#) [spectral estimation](#) [structure representation](#)**Author Keywords**

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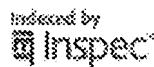
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Automated direct patterned wafer inspection

Khalai, B.H. Aghajan, H.K. Kailath, T.

Dept. of Electr. Eng., Stanford Univ., CA, USA;

This paper appears in: Applications of Computer Vision, Proceedings, 1992., IEEE Workshop on

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Abstract

A self-reference technique is developed for detecting the location of defects in repeated pattern wafers and masks. The application area of the proposed method includes inspection of memory chips, shift registers, switch capacitors, and CCD arrays. Using high resolution spectral estimation algorithms, the proposed technique first extracts the period and structure of repeated patterns from the image to sub-pixel resolution, and then produces a defect-free reference image for making comparison with the actual image. Since the technique acquires all its needed information from a single image, there is no need for a database image, a scaling procedure, or any a-priori knowledge about the repetition period of the patterns

Index Terms

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Controlled Indexing

automatic optical inspection integrated circuit testing monolithic integrated circuits

Non-controlled Indexing

CCD arrays VLSI wafers defect location defect-free reference image high resolution spectral estimation algorithms
memory chips repeated pattern wafers self-reference technique shift registers sub-pixel resolution switch capacitors wafer inspection

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Dept. of Electr. Eng., Stanford Univ., CA, USA;

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